

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) 72478-3400		Application Number 09/997,988		
				Applicant(s) Masaki Aoki et al.				
				Filing Date November 29, 2001		Group Art Unit 1722		
U. S. PATENT DOCUMENTS								
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
		4,717,584	1.5.1988	Aoki et al.				
		4,926,095	5.15.1990	Shinoda et al.				
U.S. PATENT APPLICATION PUBLICATIONS								
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
FOREIGN PATENT DOCUMENTS								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
		61-287032	12.17.1986	Japan (See USP 4,717,584)			X	
		2001-104774	4.17.2001	Japan w/English Abstract			X	
		2004-170394	6.17.2004	Japan w/English Abstract			X	
		90-008640	11.26.1990	Korea (See USP 4,926,095)			X	
OTHER DOCUMENTS <i>(Including Author, Title, Date, Pertinent Pages, Etc.)</i>								
		Fujii, E. et al, "NaCl-type Oxide Films Prepared by Plasma-Enhanced Metalorganic Chemical Vapor Deposition", Japanese Journal of Applied Physics, Part 2 (letters), Vol. 32, No. 10A, L1448-L1450, October. 1, 1993.						
EXAMINER				DATE CONSIDERED				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								